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cket No.: 49657-961

PATENT

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Kenji ITOGA, et al.

Serial No.: 09/769,490

Group Art Unit: 2882

Filed: January 26, 2001

Examiner: C. Kao

For:

X-RAY EXPOSURE APPARATUS, X-RAY EXPOSURE METHOD, X-RAY MASK, X-

RAY MIRROR, SYNCHROTRON RADIATION APPARATUS, SYNCHROTRON

RADIATION METHOD AND SEMICONDUCTOR DEVICE

CORRECTED SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents Washington, DC 20231

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Supplemental Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

The relevance of each non-English language reference, if any, is discussed in the present specification.

WDC99 685097-1.049657.0961

09/769,490

This Corrected Supplemental Information Disclosure Statement is being filed to correct errors on the PTO-1449 Forms filed on November 25, 2002.

Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account 500417 and please credit any excess fees to such deposit account.

Respectfully submitted,

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Date: January 16, 2003